

## Supporting Information

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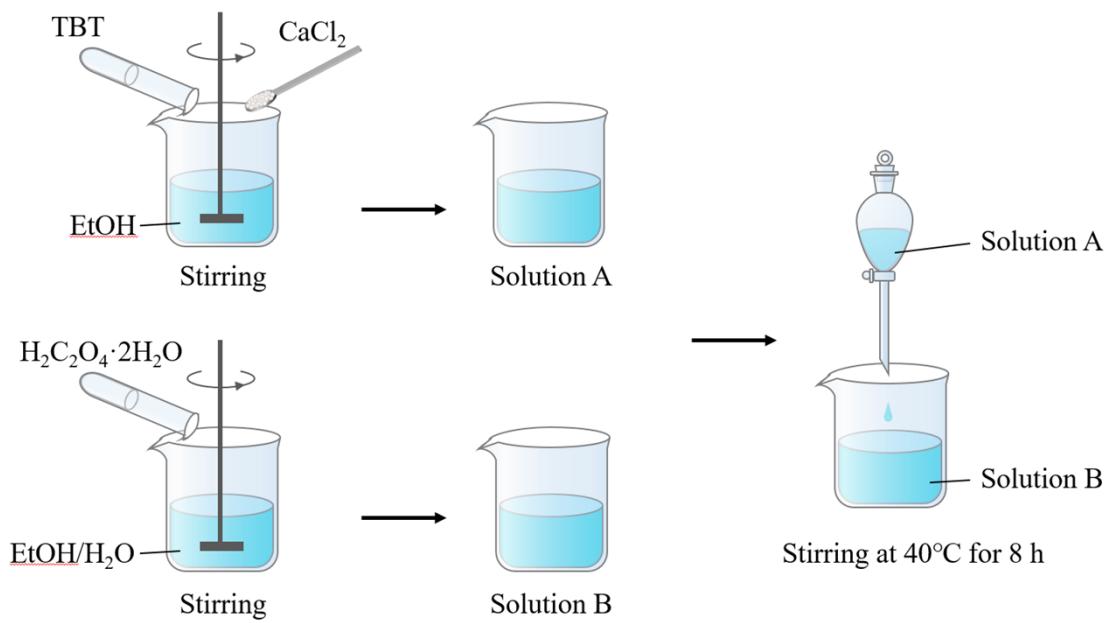
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**Figure S3.** Optical photograph of the ER fluid with the concentration of 3.5 g/mL

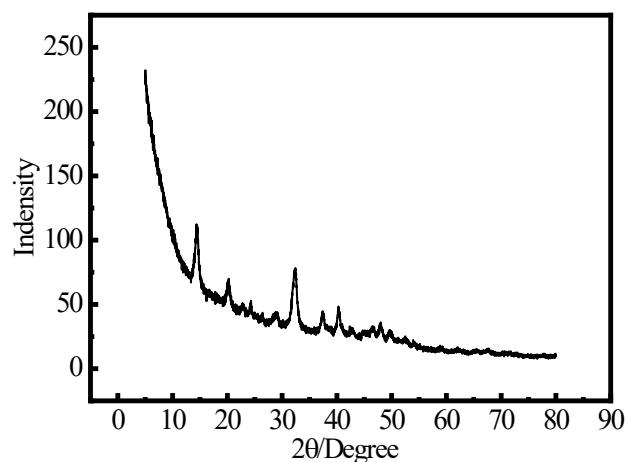
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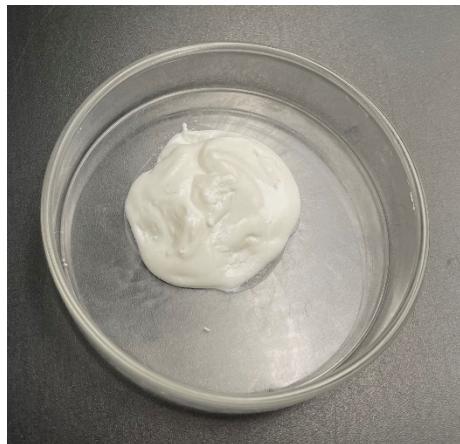
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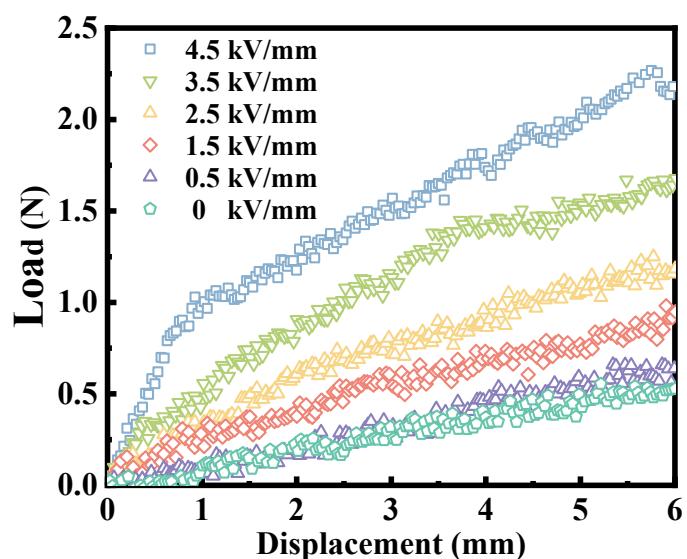
**Fig. S1** The fabrication process of CTO particles



**Fig. S2** The XRD pattern of CTO particles.



**Fig. S3** Optical photograph of the ER fluid with the concentration of 3.5 g/mL.



**Fig. S4** Load as a function of bending displacement in the deformation process of 0-6 mm.